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PATENT NUMBER AND  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10085753	FILING DATE 02/28/2002	CLASS 438/134	SUBCLASS 924.3	GAU 282 1746	EXAMINER KORMANOV
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\*\*CONTINUING DATA VERIFIED:

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\*\* FOREIGN APPLICATIONS VERIFIED:

JAPAN 2001-059776 03/05/2001

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO
35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		TI-31620
Verified and Acknowledged Examiners's initials		
TITLE : Method and device for removing particles on semiconductor wafers		
U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)		

ISSUE FEE		Assistant Examiner		Total Claims		Figs. Claimed	
Amount Due	Date Paid						
		Primary Examiner		DRAWING			
				Sheets Drawn Figs. Drawn First Fig.			
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		Application Examiner			
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